



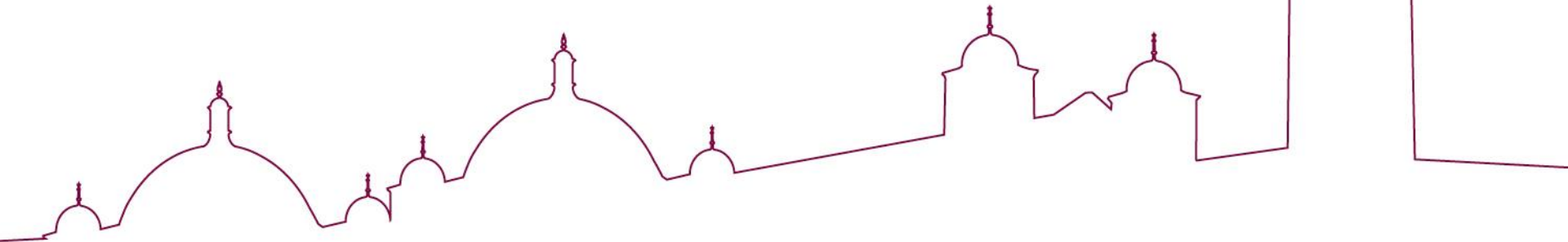
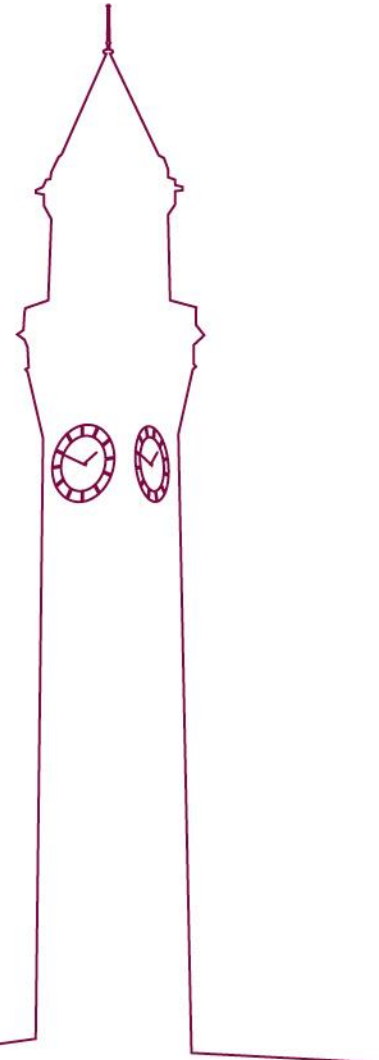
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Preliminary Test Results of LGADs from Teledyne e2v for the LHC's High-Luminosity Upgrade

J.Mulvey^{1, a)}, I. Kopsalis¹, P. Allport¹, L. Gonella¹, M. Gazi^{2, 3}, D. Bortoletto², R. Plackett², E.G.Villani³, S. McMahon³, K. Stefanov⁴, D. Jordan⁵

¹University of Birmingham ²University of Oxford ³STFC Rutherford Appleton
Laboratory ⁴The Open University ⁵Teledyne e2v





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Overview of Sensor Design

IV Results

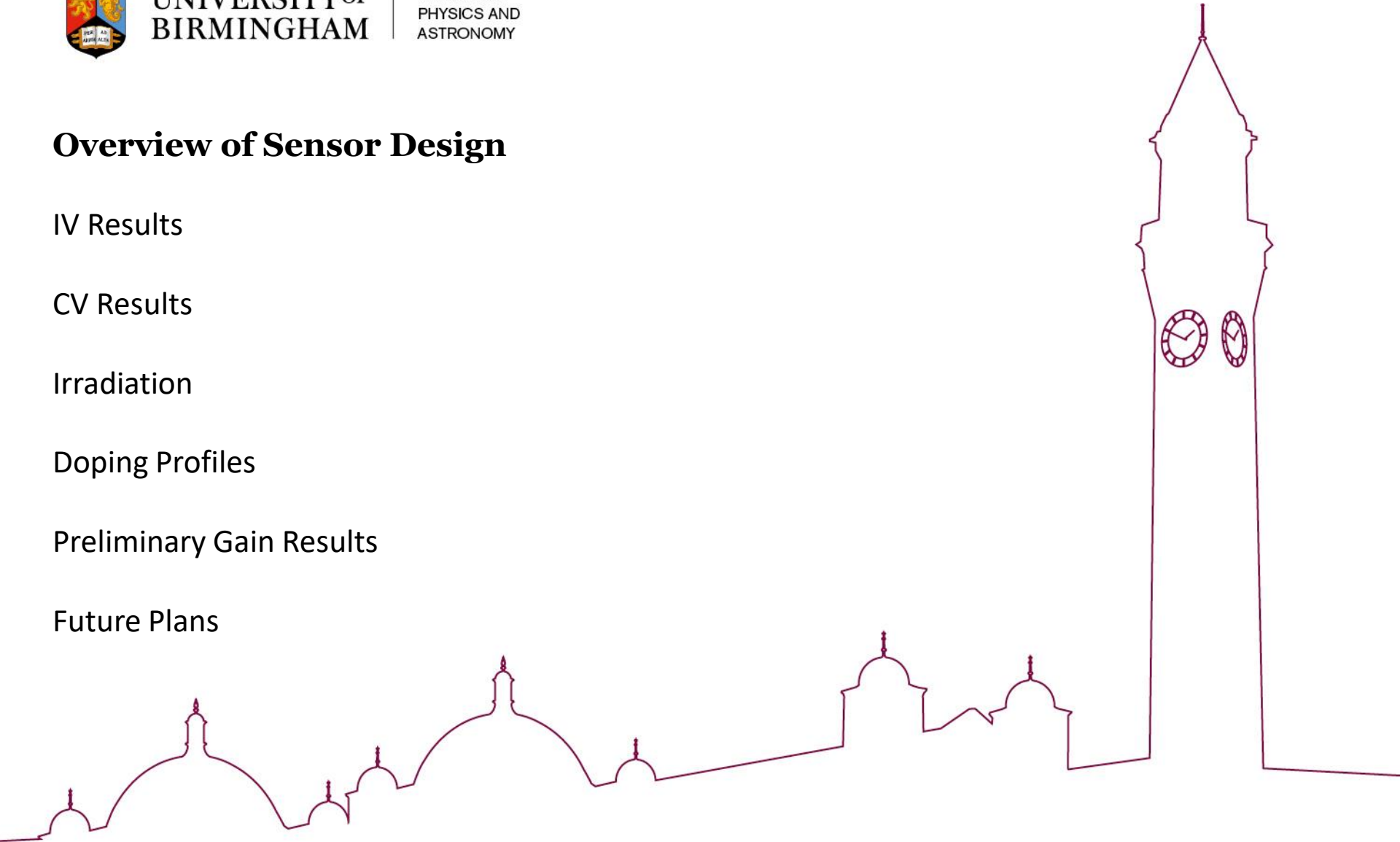
CV Results

Irradiation

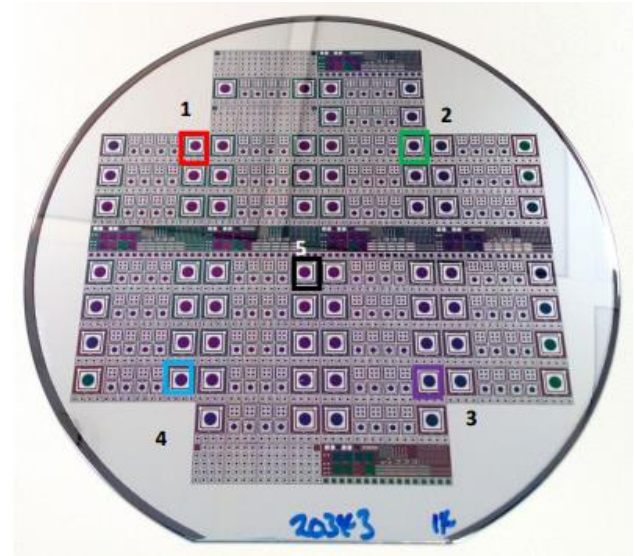
Doping Profiles

Preliminary Gain Results

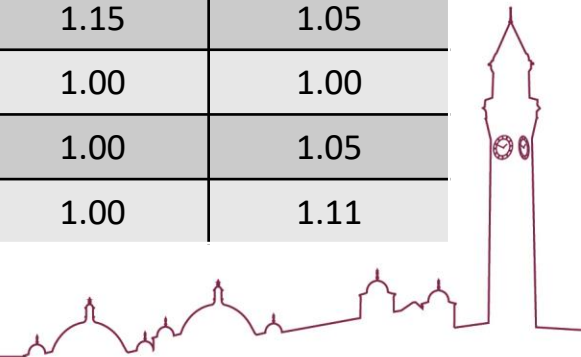
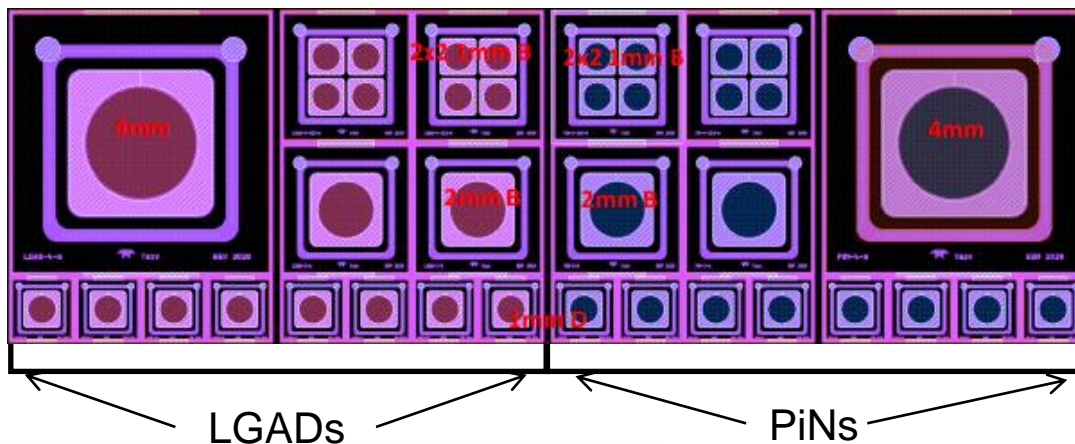
Future Plans



- Collaboration between the University of Birmingham, University of Oxford and the Open University
- We are working closely with the UK foundry at Teledyne e2v whom already have a large production volume set up for CCDs
- We are currently testing our first batch of 22 wafers, which come in triplets of the same implant energy and dose
- Each wafer contains sets of LGADs and PiNs, with and without the gain layer implant respectively
- There are 4 different size configurations: 1 mm, 2 mm, 4 mm, and 2x2 arrays of 1 mm
- Each size also has different “flavours” where properties such as the distance from the pad to the guard ring is varied



Wafer code	Normalised Dose (D)	Normalised Energy (E)
A	1.07	1.11
B	1.07	1.05
C	1.07	1.00
D	0.92	1.05
E	1.15	1.05
F	1.00	1.00
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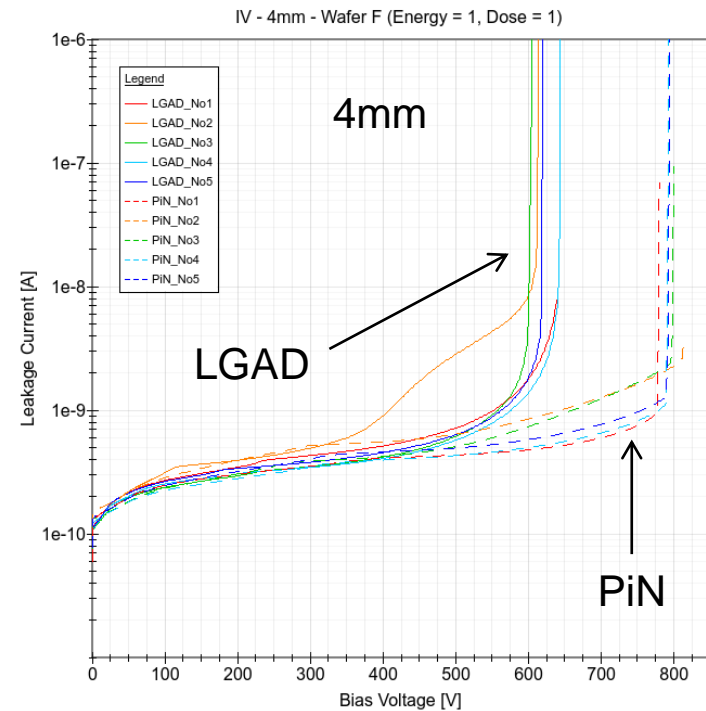
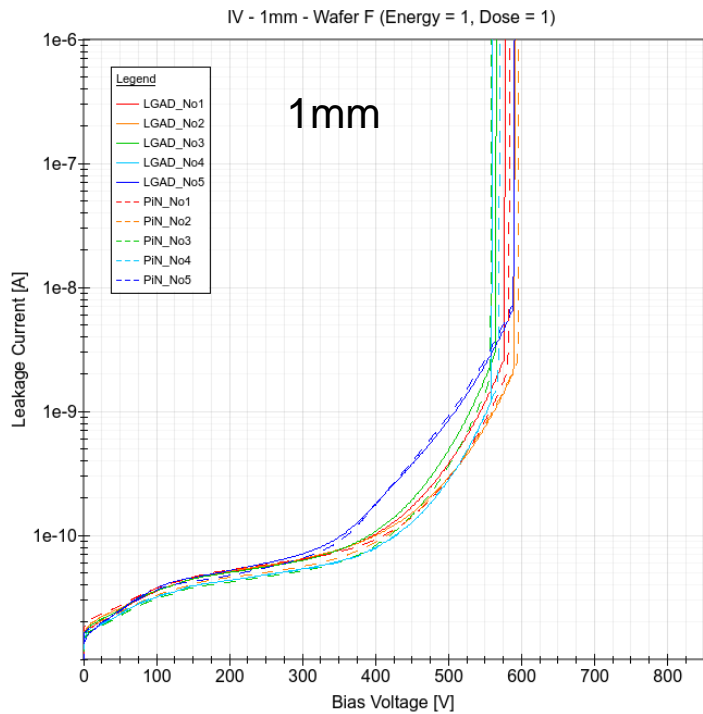
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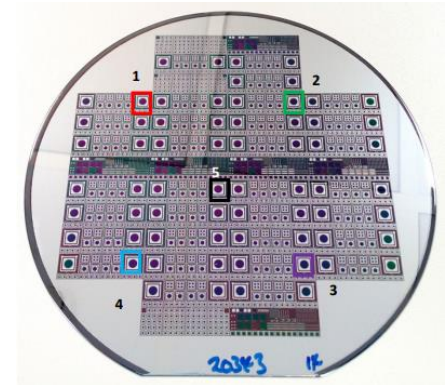
Preliminary Gain Results

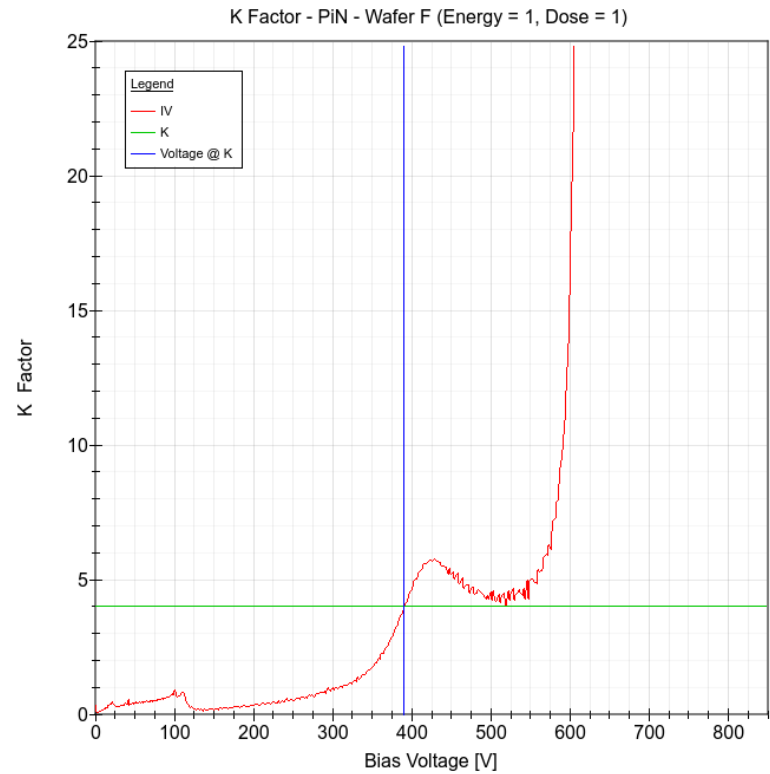
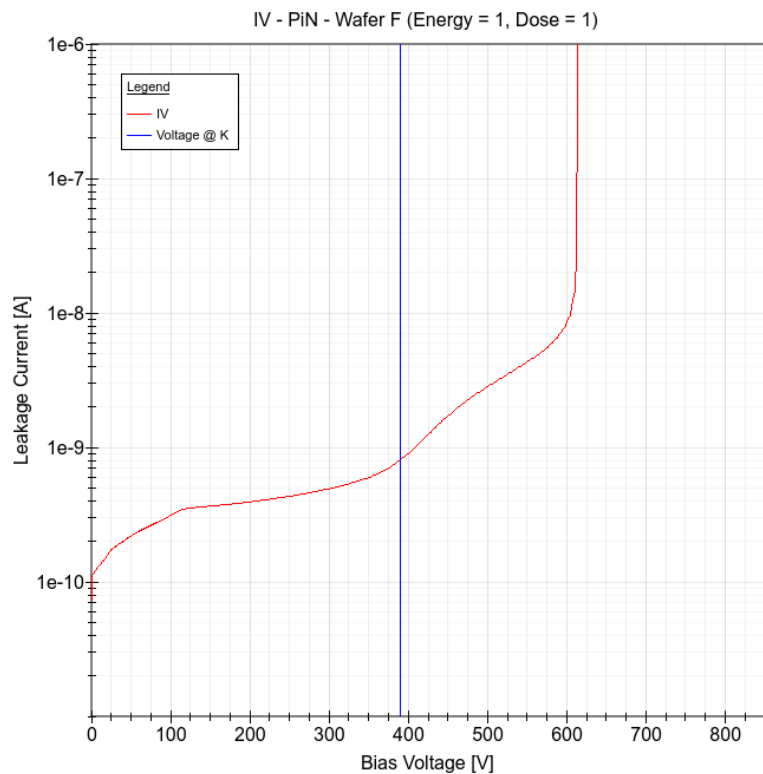
Future Plans





- While the devices are still on the wafer, we conducted IVs on a sample of locations across the wafer to check wafer uniformity (Typically, only 3 of the 5 locations were used to speed up the process)
- In the figure we have a sample of IVs for both PiN and LGAD from a wafer with an implant of Low Energy and Medium Dose
- There is clearly some differences within the same wafer LGAD to LGAD, but this nothing unusual. We also see a difference between LGAD and PiNs for 4mm devices

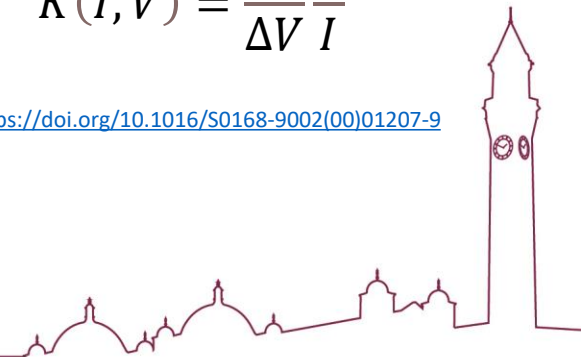




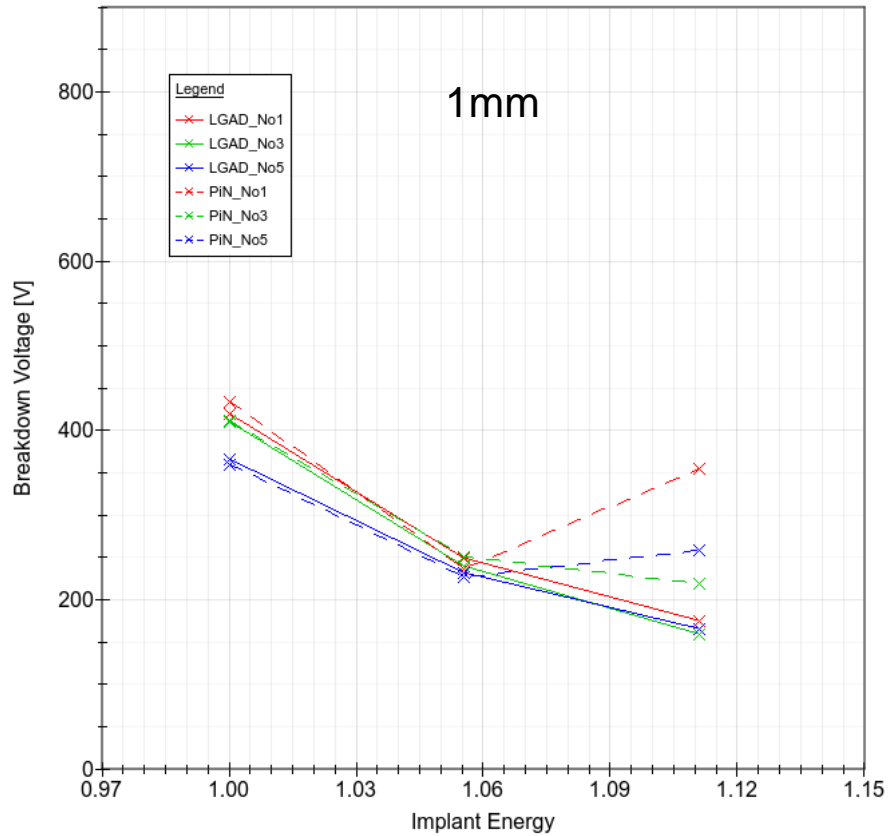
- For better comparison between wafers, we do a breakdown characterisation of the IVs
- We do this using the ‘K-Factor’ method, with formulae shown below.
- The K-Factor gives an indication to breakdown which is defined as a significant increase in the leakage current as function of voltage.
- We define a threshold of $K = 4$ as a ‘soft’ breakdown, and as soon as the K-Factor reaches this value, we record the voltage.

$$K(I, V) = \frac{\Delta I}{\Delta V} \frac{V}{I}$$

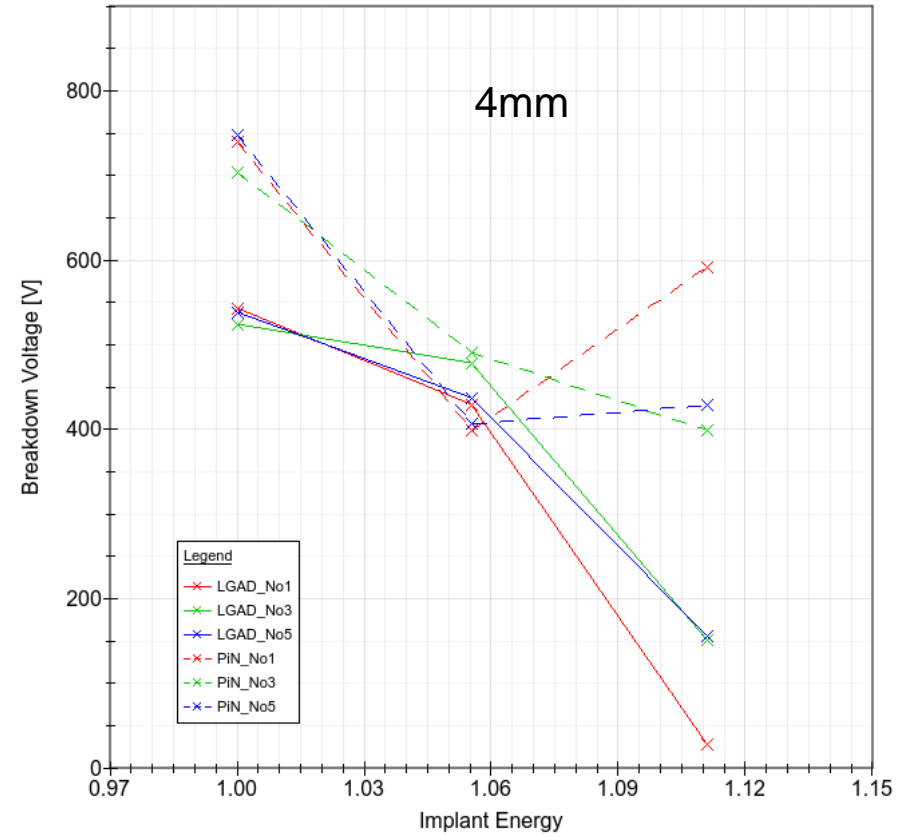
[https://doi.org/10.1016/S0168-9002\(00\)01207-9](https://doi.org/10.1016/S0168-9002(00)01207-9)



K Factor (4) Characterisation - 1mm Devices

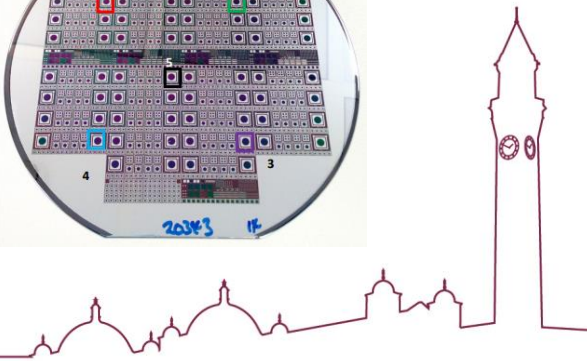
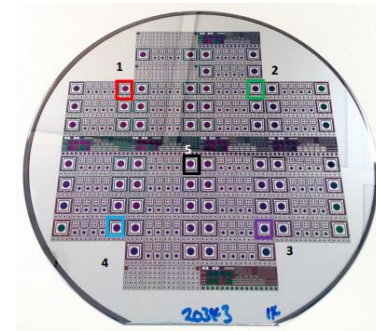


K Factor (4) Characterisation - 4mm Devices



- Having identified the breakdown voltage, we can plot this against wafer implant energy and see a general decrease in breakdown voltage
- We can see some variation within wafers as well as the difference between PiN and LGAD, which is less apparent for the 1mm devices

Wafer code	Normalised Dose (D)	Normalised Energy (E)
A	1.07	1.11
B	1.07	1.05
C	1.07	1.00
D	0.92	1.05
E	1.15	1.05
F	1.00	1.00
G	1.00	1.05
H	1.00	1.11





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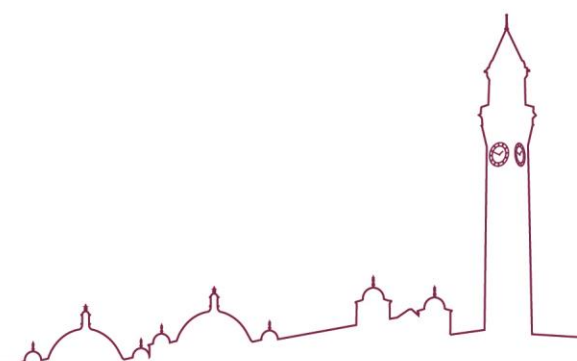
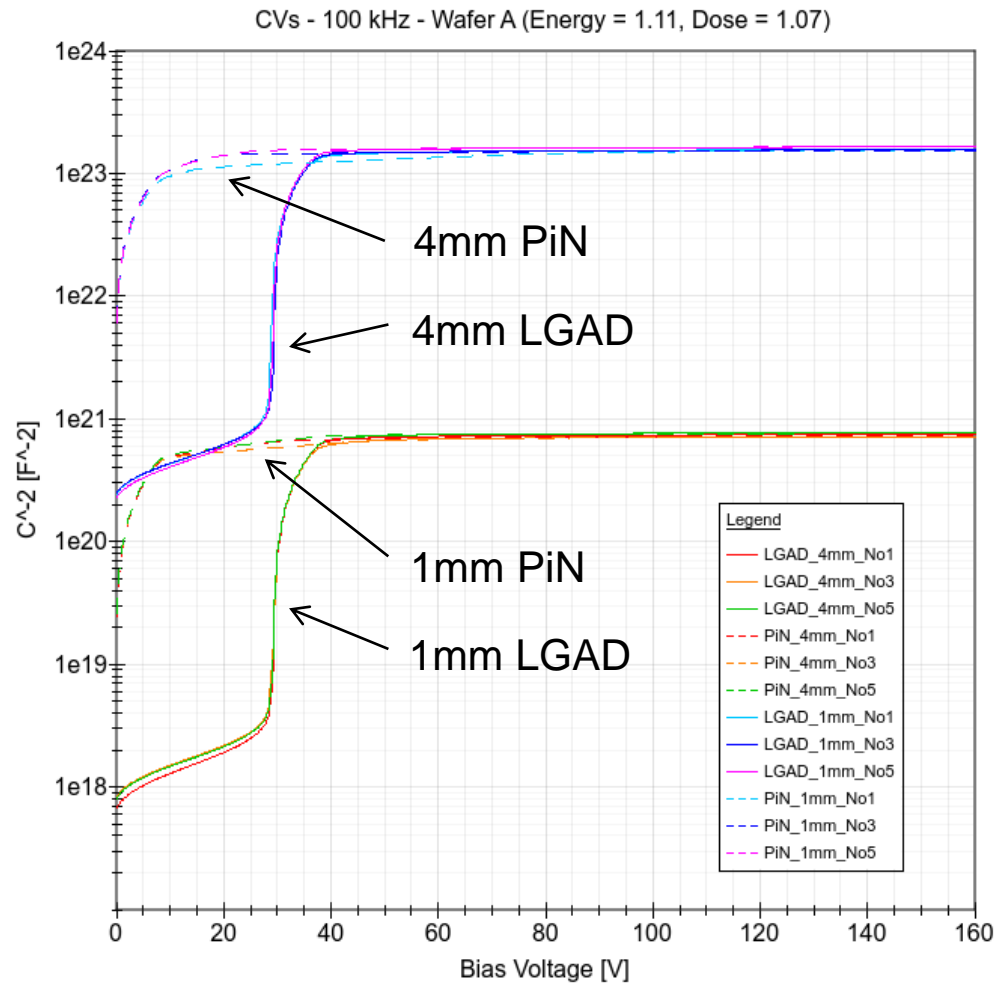
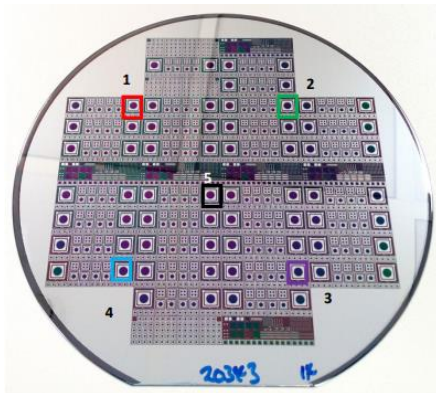
Doping Profiles

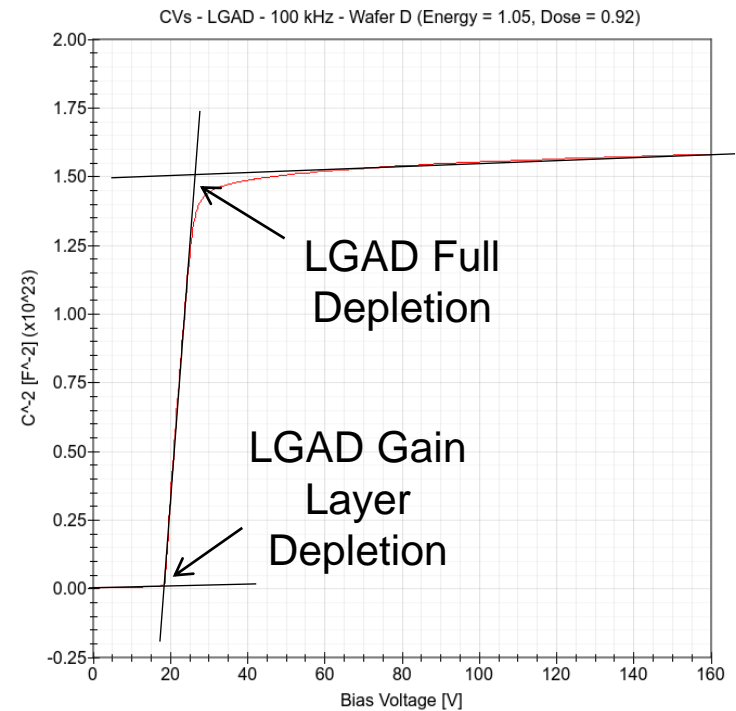
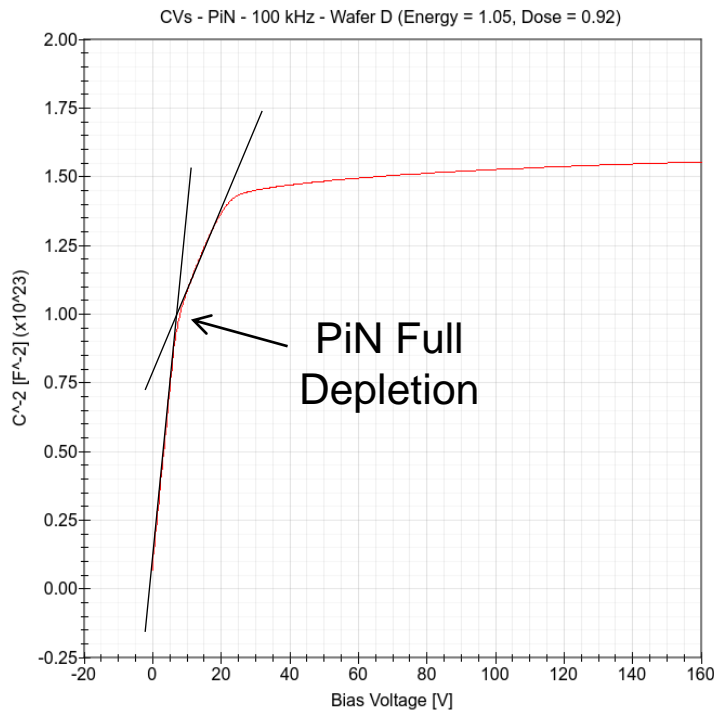
Preliminary Gain Results

Future Plans



- Similarly to IVs, we measured CVs for a sample of locations across wafers.
- In the figure we have a sample of CVs for both PiN and LGAD from a wafer with an implant of Low Energy and Medium Dose
- We were also able to test multiple frequencies (10 kHz, 100 kHz and 1 MHz). Just 100 kHz is shown here
- Here, we see much better wafer uniformity. We also see a clear impact of the gain layer in the form of an offset of around 30V in this case

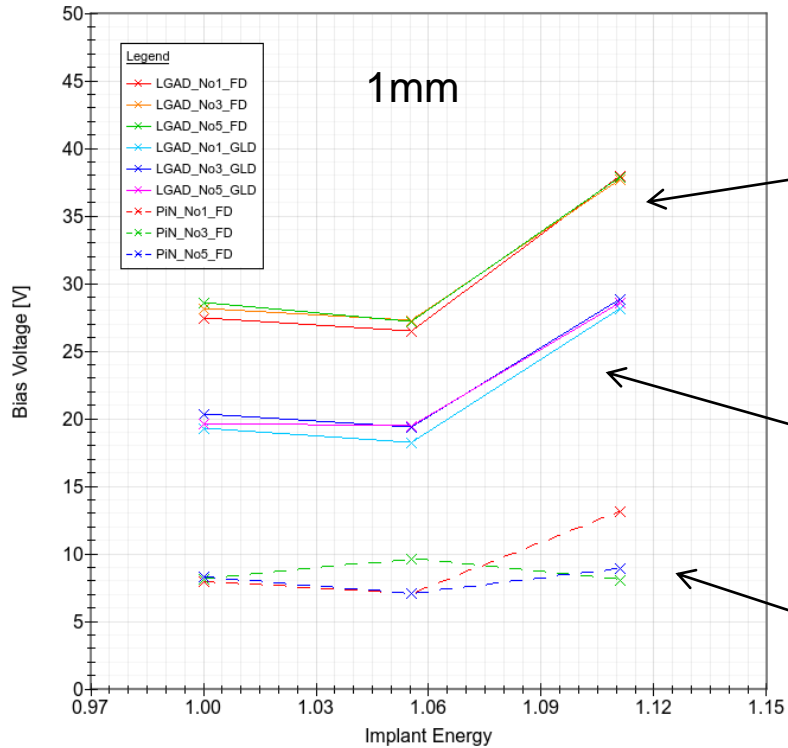




- To compare again across wafers, we can again identify specific voltages of interest.
- For the LGAD we have full depletion voltage and gain layer depletion voltage.
- PiNs only have the full depletion voltage.
- We identify these points by fitting straight lines to sections of the CV curve and finding the intercept.



CV Characterisation - 1mm Devices - 100 kHz

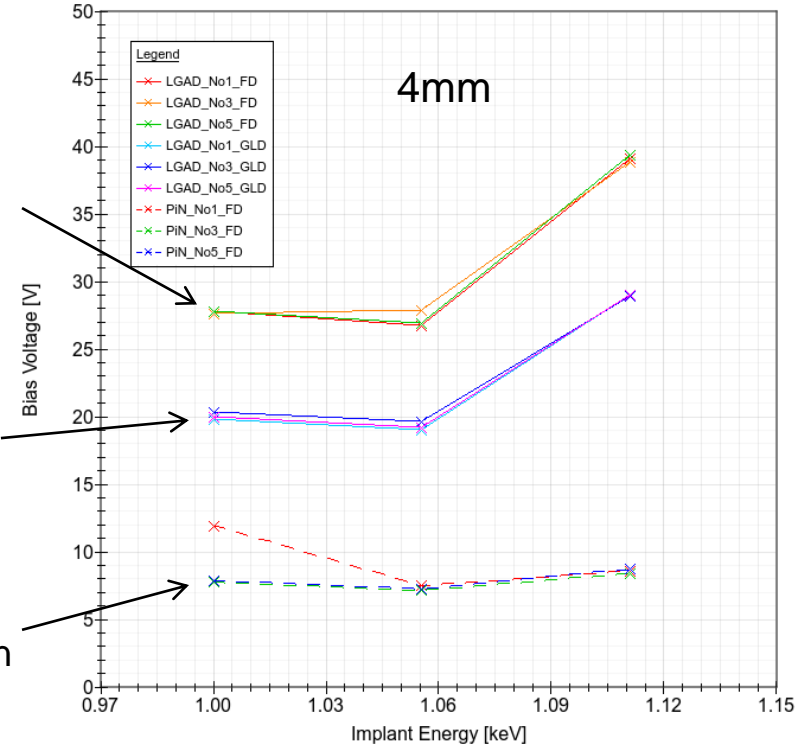


LGAD Full Depletion

LGAD Gain Layer Depletion

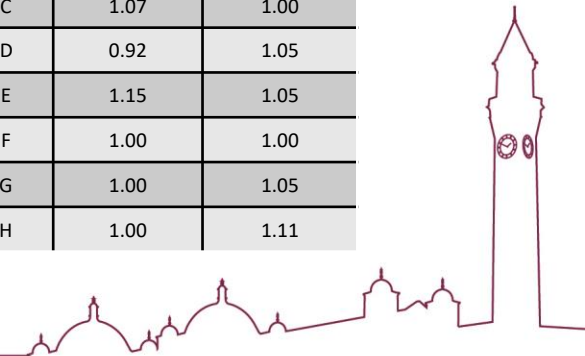
PiN Full Depletion

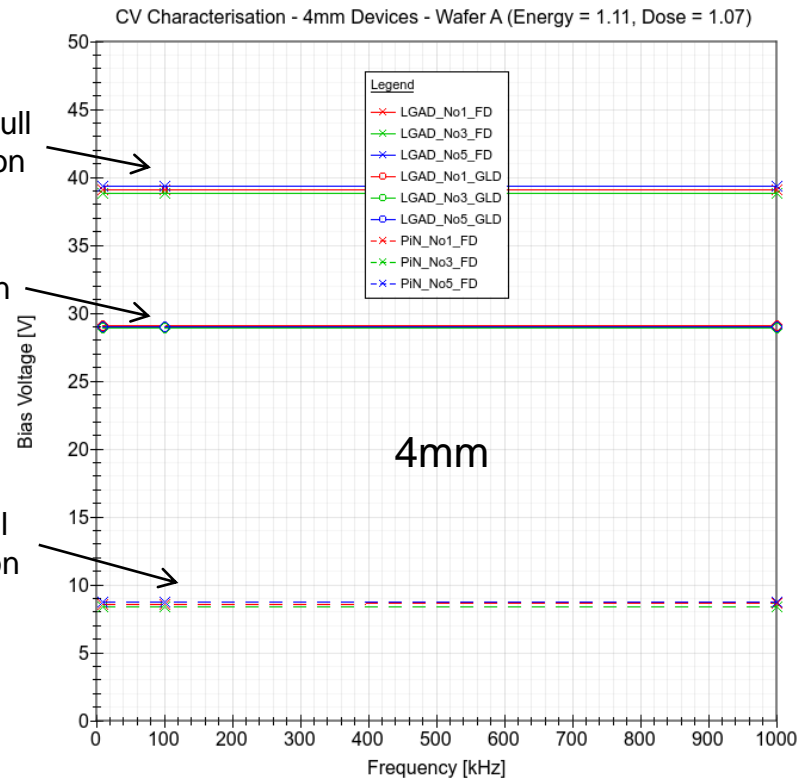
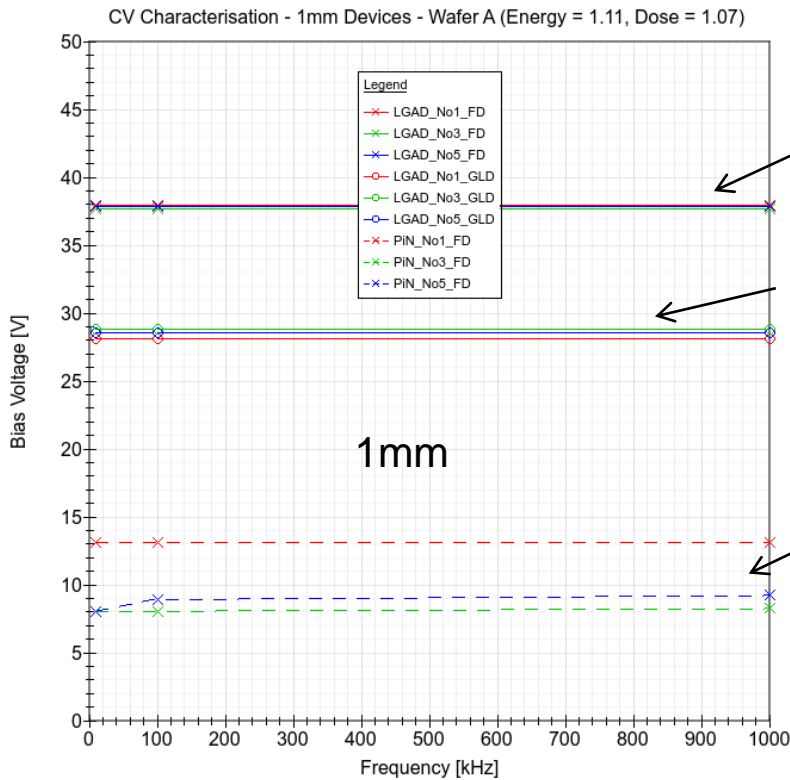
CV Characterisation - 4mm Devices - 100 kHz



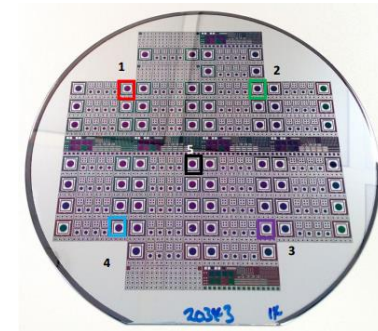
- The depletion voltages can then be plotted against gain layer implant energy
- In all cases, we see really good wafer uniformity for LGADs with a clear increase in depletion voltages at higher implant energies.
- For the PiNs, the depletion voltage is unchanged by the gain layer implant energy as expected, but there is some variability.
- Here only results for 100 kHz is shown

Wafer code	Normalised Dose (D)	Normalised Energy (E)
A	1.07	1.11
B	1.07	1.05
C	1.07	1.00
D	0.92	1.05
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- Plotting the depletion voltages against frequency shows no trend
- We see the same non-uniformity for PiNs
- These results are from the higher implant energy only. Other implant energies behave very similarly against frequency





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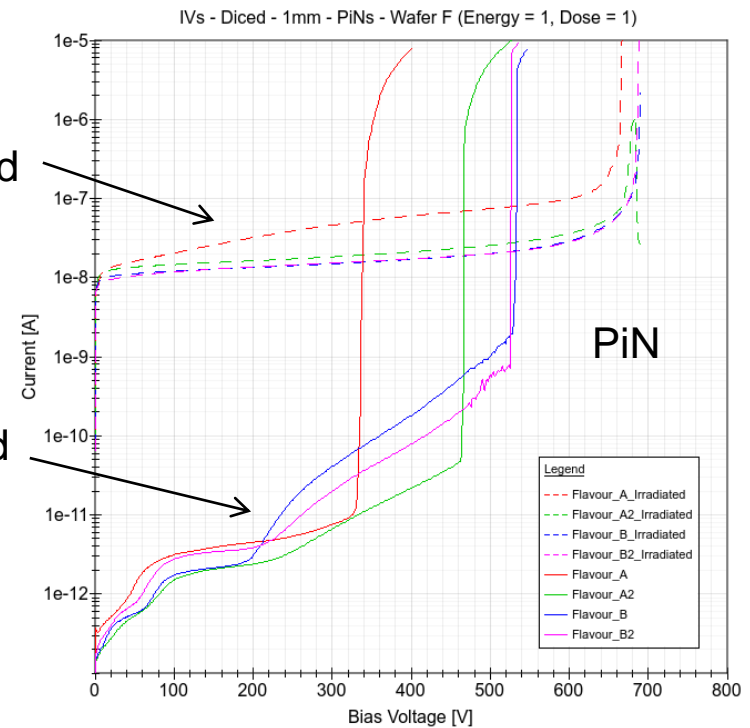
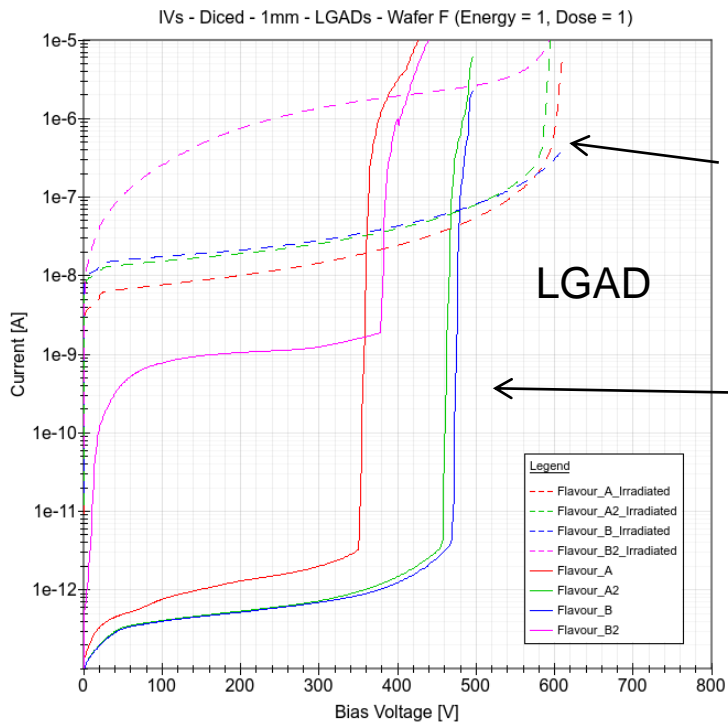
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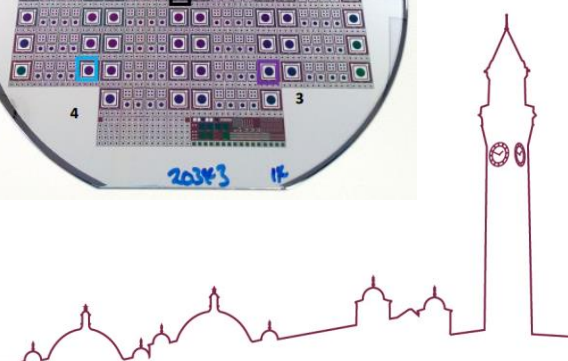
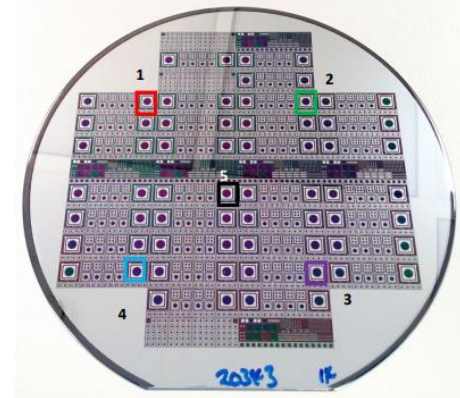




- Two diced devices were sent for irradiation at $5e14$ 1 MeV n_{eq}/cm^2 .
- IVs were measured before and after irradiation and pre-annealing. The former were temperature corrected from 22 deg C to -20 deg C with the following formula:

$$I(T_{-20}) = I(T_{22}) \left(\frac{T_{-20}}{T_{22}} \right)^2 \exp \left(\frac{-1.2}{2k_B} \left(\frac{1}{T_{-20}} - \frac{1}{T_{22}} \right) \right)$$

- As expected, there is a clear increase in leakage current, but all devices which had a high breakdown voltages pre-irradiation, still have that high breakdown. Some devices were damaged by the laser dicing process





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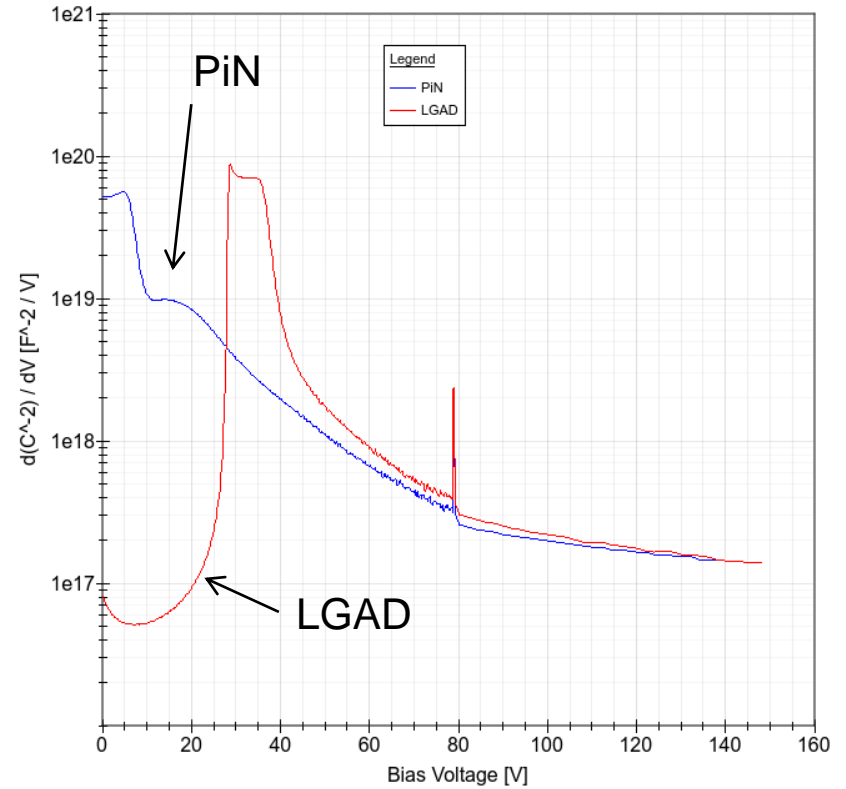
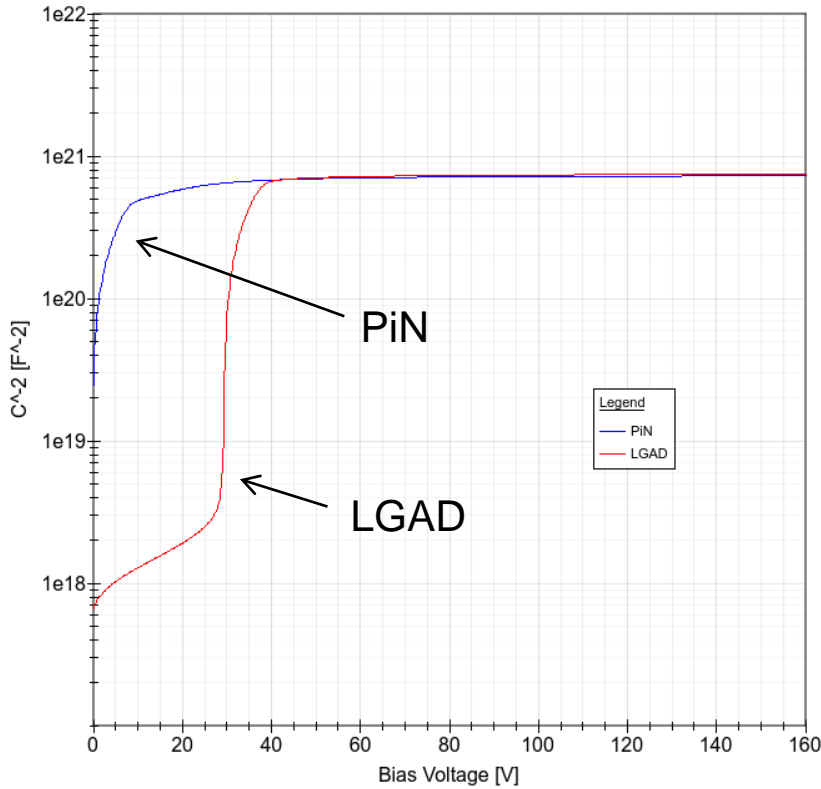
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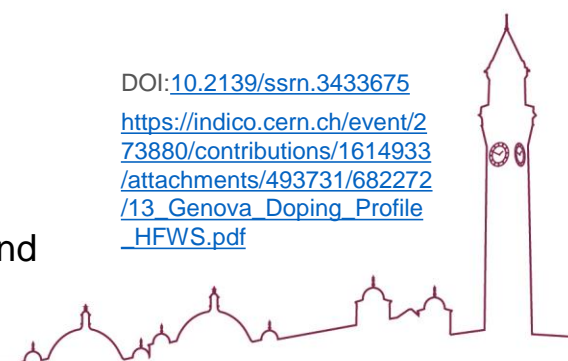
- Information about the doping profile is extractable from the CVs
- Firstly, we calculate the gradient as a function of bias voltage
- From the gradient, the doping concentration can be estimated

$$N = \frac{2}{d \left(\frac{1}{C^2} \right)} \cdot \frac{1}{\epsilon q A^2}$$

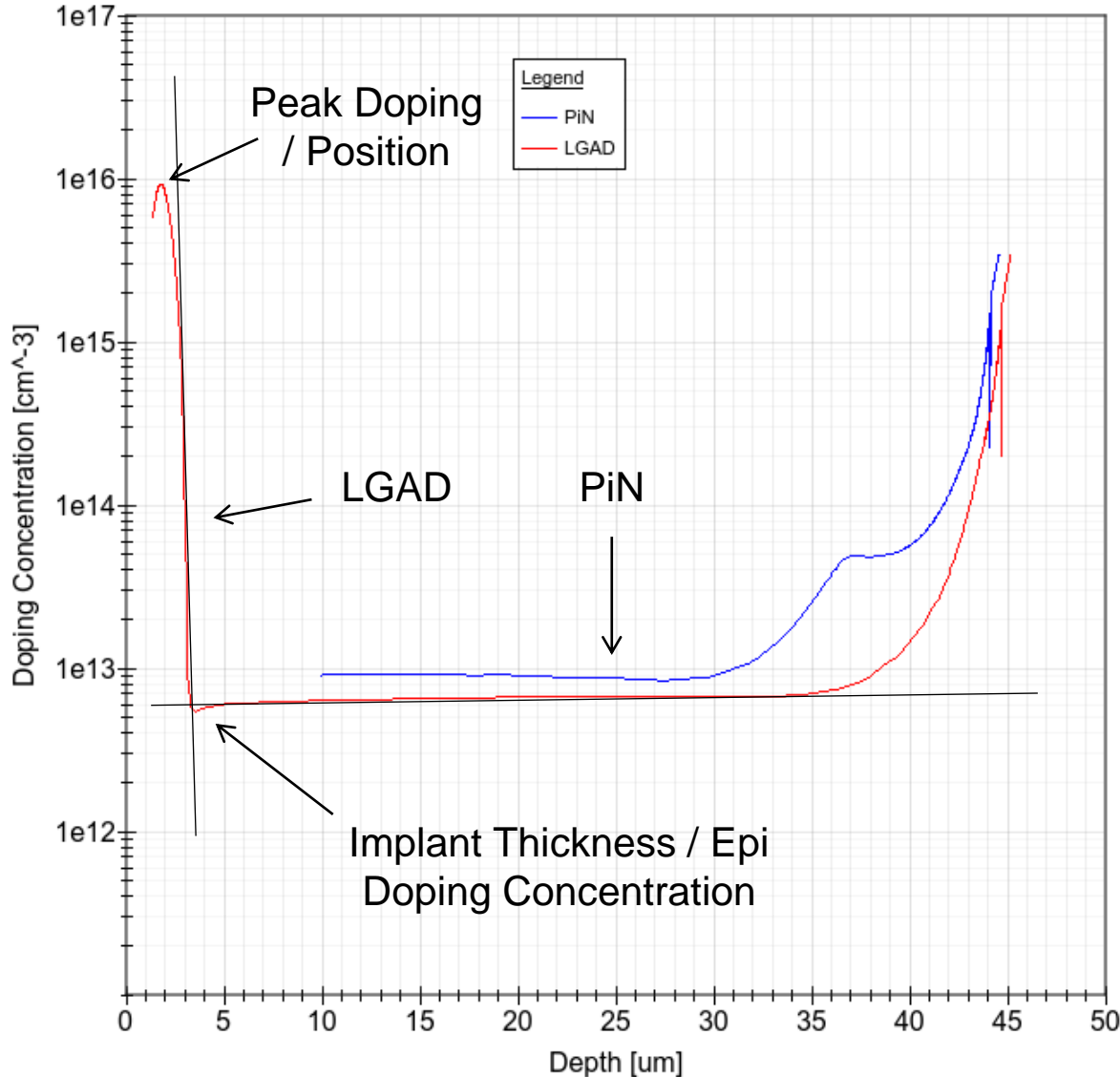
$$x = \epsilon A / C$$

N is the doping concentration and x is the depth

DOI: [10.2139/ssrn.3433675](https://doi.org/10.2139/ssrn.3433675)
https://indico.cern.ch/event/273880/contributions/1614933/attachments/493731/682272/13_Genova_Doping_Profile_HFWS.pdf



CV Characterisation - 4mm Devices - Wafer A (Energy = 1.11, Dose = 1.07)



- From the gradient, the doping concentration can be calculated
- An approximate depth can be mapped capacitance at each bias voltage
- As with the CVs, fittings can be made, and key features such as the peak doping, and gain layer depth can be extracted

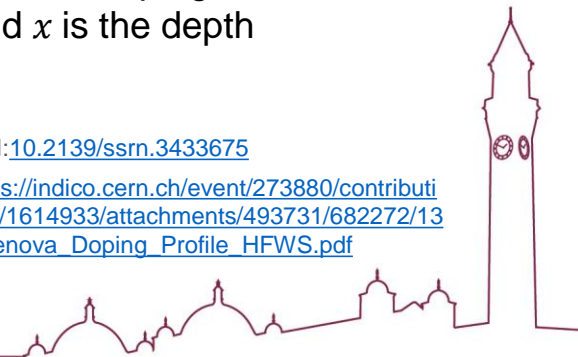
$$N = \frac{2}{d \left(\frac{1}{C^2} \right)} \cdot \frac{1}{\epsilon q A^2}$$

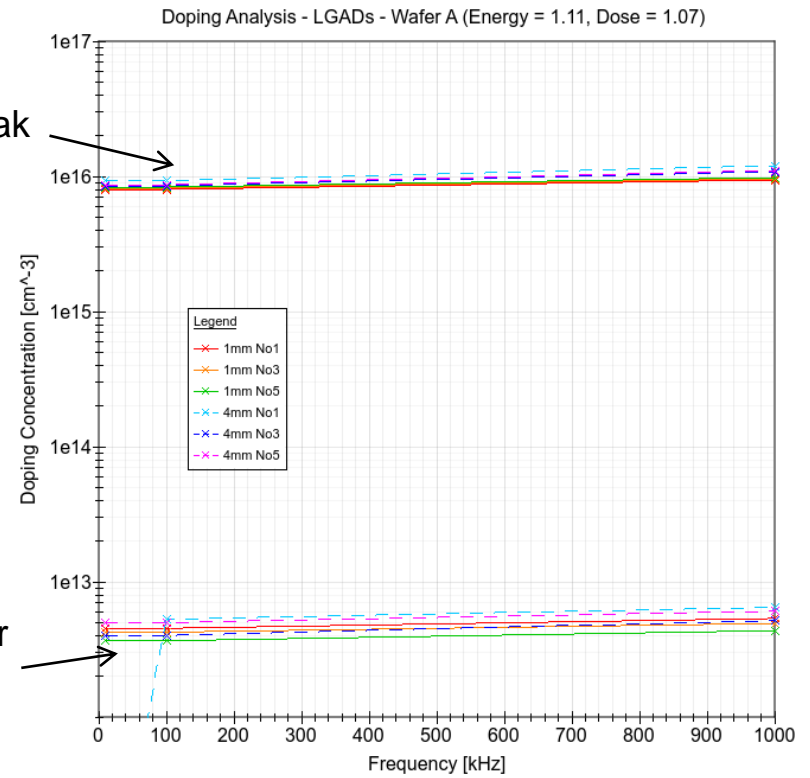
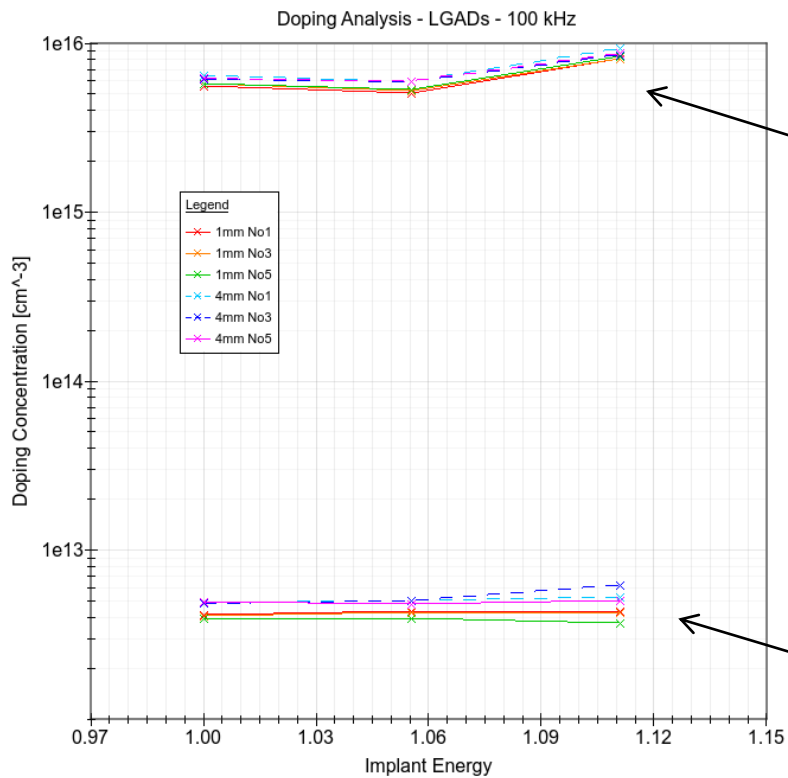
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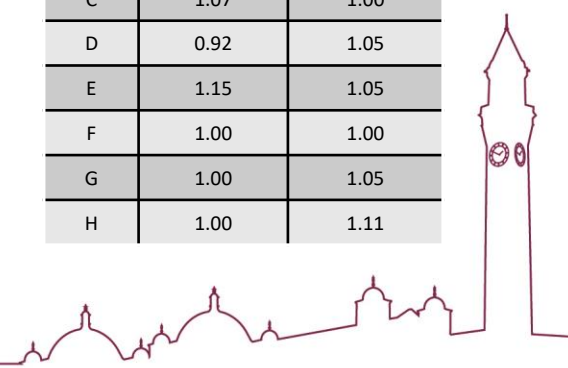
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- We can now plot the extracted doping concentrations for two key area: Peak doping in the implant layer and the baseline doping of the epi layer
- We see a slight dependency on implant energy for the peak doping, but not for the epi layer, as expected
- We see no real dependency on the size of the device, which is also to be expected
- We see in all cases a slight dependency on frequency. This is evidence that we can only crudely extract doping, showing the limitations of our approach

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A	1.07	1.11
B	1.07	1.05
C	1.07	1.00
D	0.92	1.05
E	1.15	1.05
F	1.00	1.00
G	1.00	1.05
H	1.00	1.11





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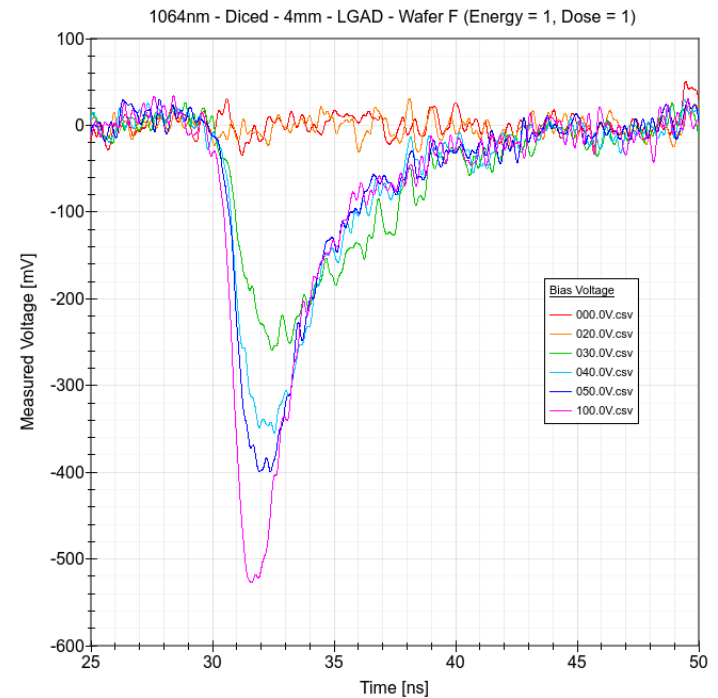
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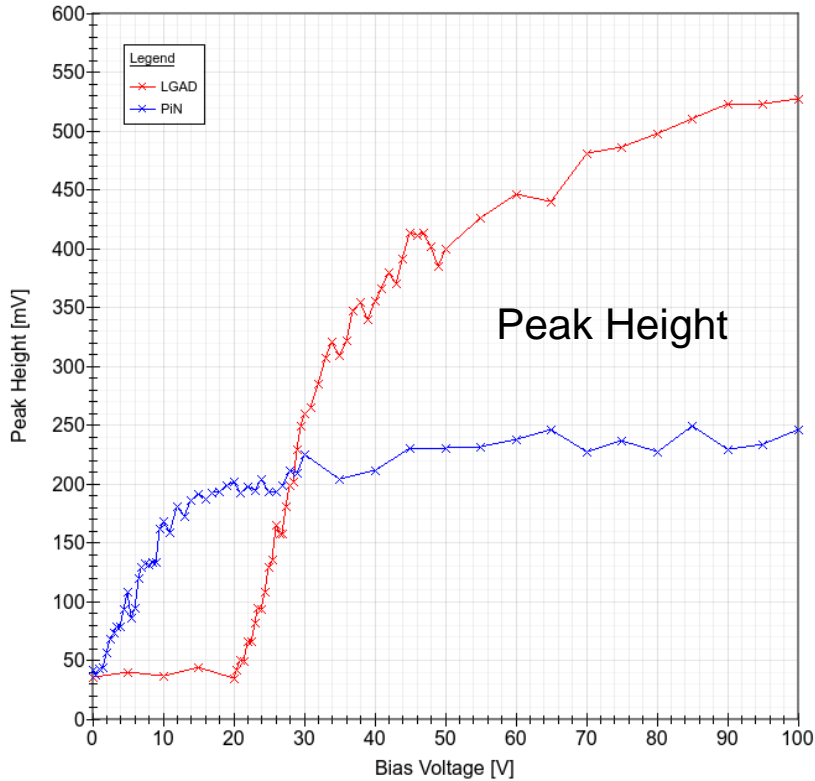




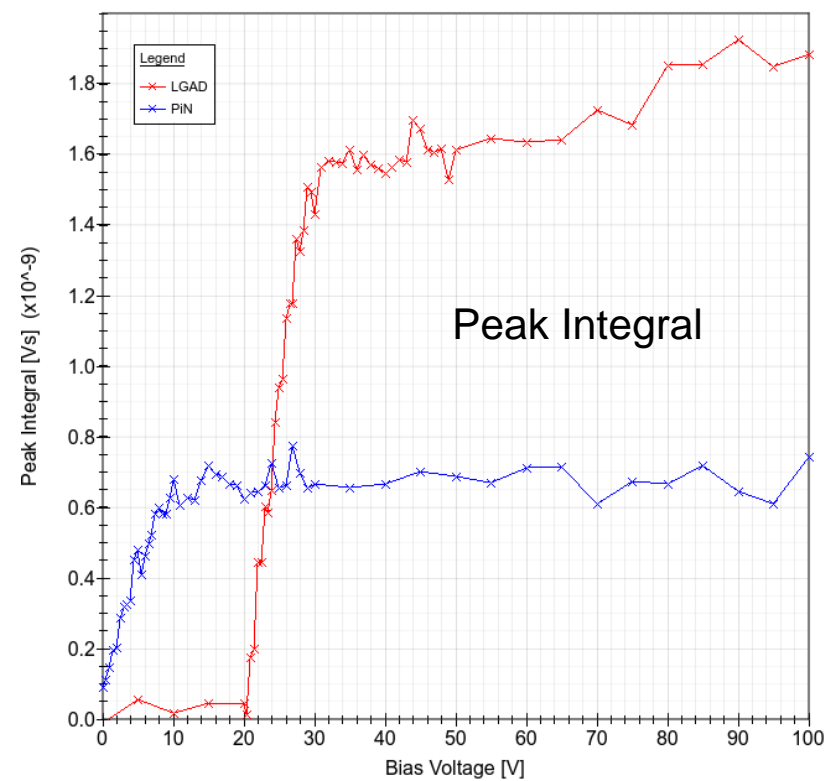
- In order to gain an understanding our LGADs intrinsic gain, we inject charges via a 1064nm IR laser
- We do this for a range of bias voltages, and the output signal is then amplified by a Particulars AM-02 A RF amplifier and the signal is recorded. (Examples of the recorded signal is shown in the figure)
- We can use the height of the signal to indicate the charge collected, but by integrating the signal, we extract all of the charge collected
- We can understand the gain of our LGAD by comparing it to a PiN (which we assume a gain of around 1)



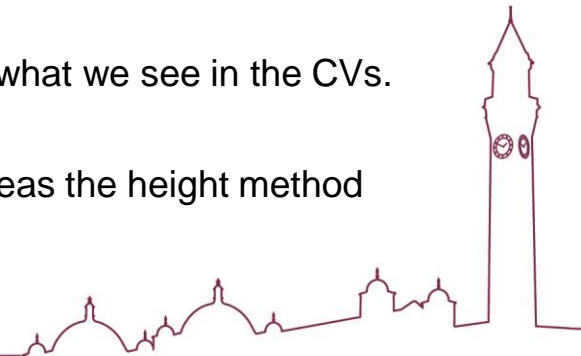
"Fast Amp" - 1064nm - 40% (1320mV) - Wafer F (Energy = 1, Dose = 1)

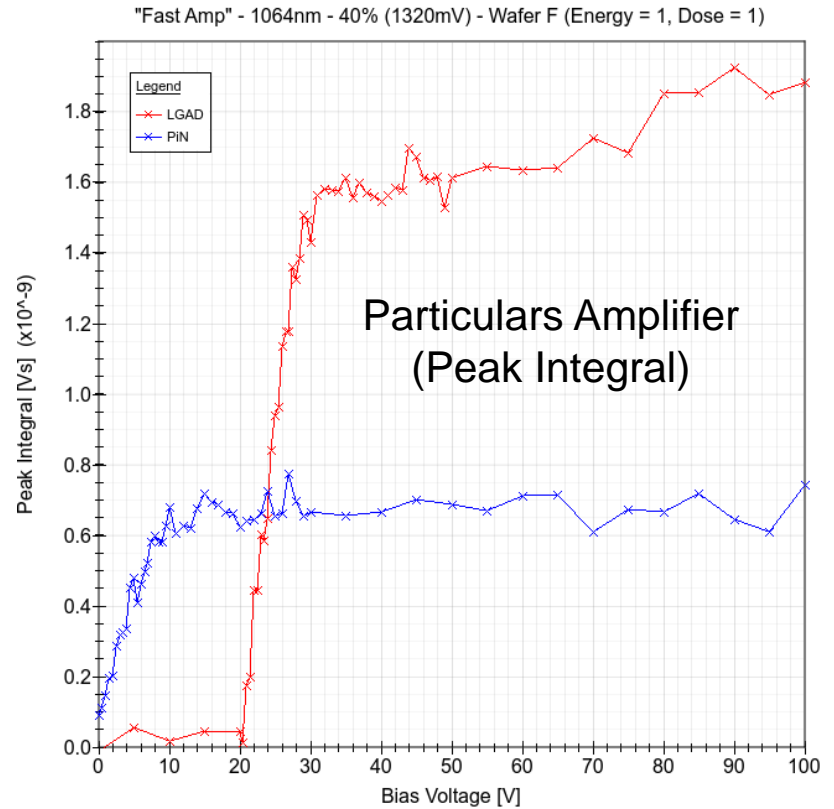
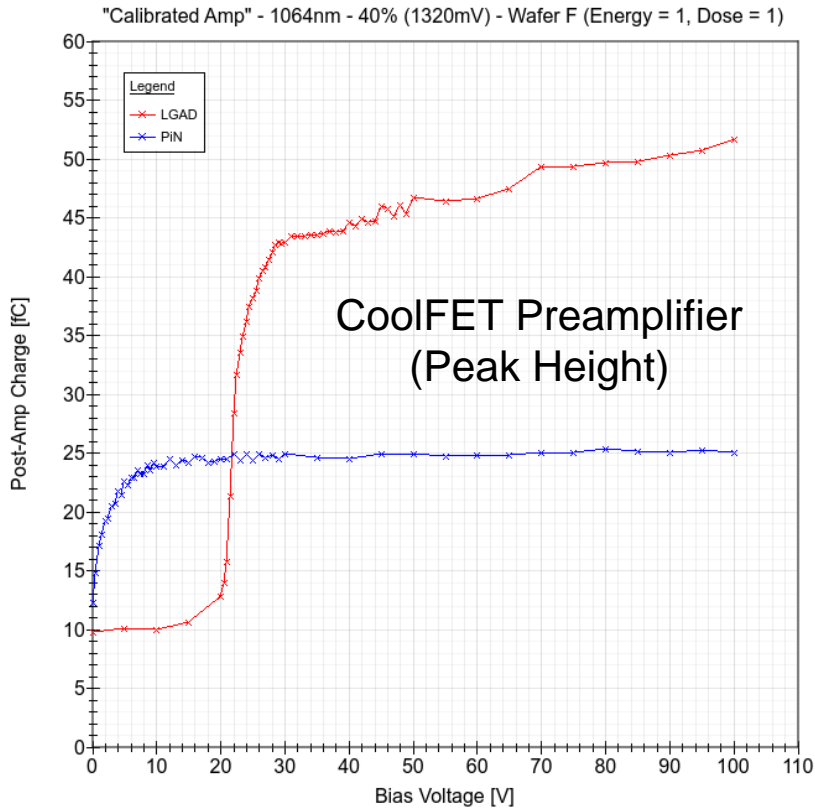


"Fast Amp" - 1064nm - 40% (1320mV) - Wafer F (Energy = 1, Dose = 1)



- Both methods (peak height vs integration) show delay in full depletion for the LGAD, caused by the gain layer implant
- The integration method shows a more sharp rise charge collection similar to what we see in the CVs.
- After full depletion, the integration method suggests a gain of around 3, whereas the height method suggests a gain of around 2 – 2.5





- We also repeated the measurements using a much slower CoolFET A250CF Preamplifier.
- For this particular amplifier we have a calibration from output voltage to charge in fC
- We see a similarly sharp rise of the LGAD from both this slower amplifier and the integral of the faster amplifier.
- The relative gain also remains similar, closer to 2 for the CoolFET





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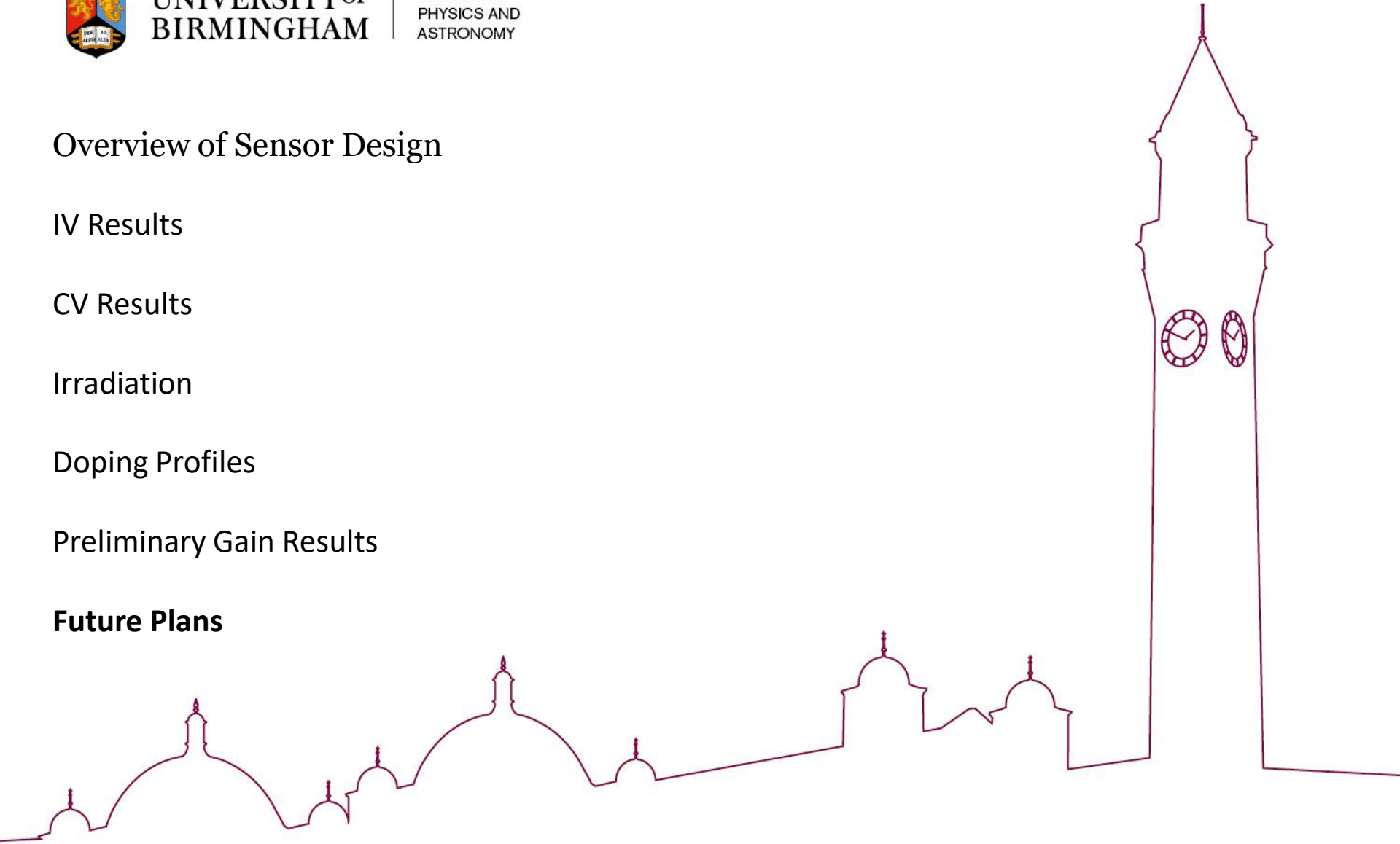
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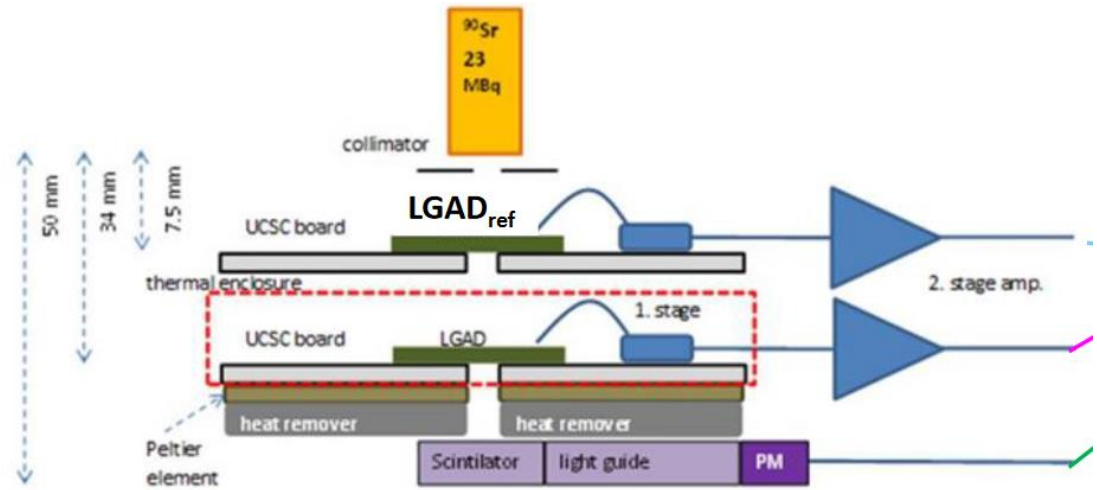
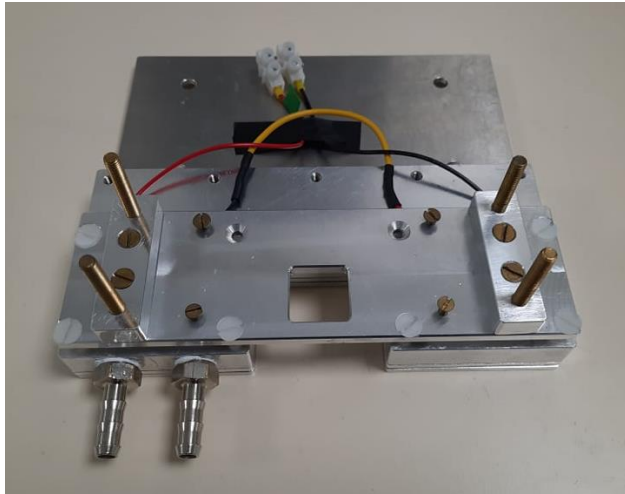
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Timing setup from Ljubljana

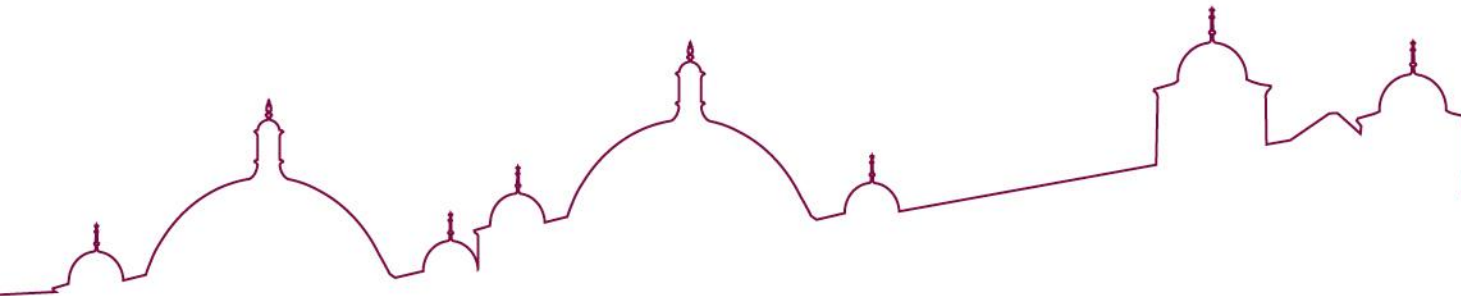
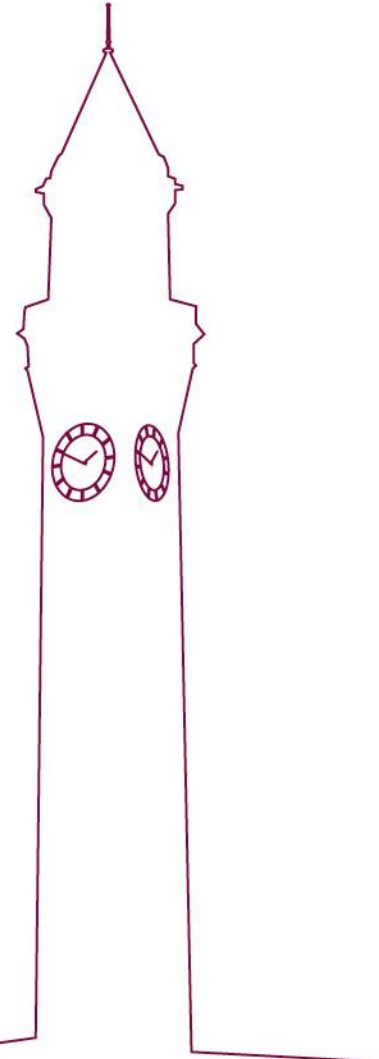
- We are currently in the process of building a setup with will allow us to measure picosecond timing resolution.
- The setup will use a Sr-90 source along with a reference LGAD and PM & Scintillator for triggering.
- We hope to finish construction and begin the first measurements over the next few months
- We'd like to thank Gregor and colleagues at Ljubljana for allowing us to use their design for the setup, as well as their continuing help with its construction





In Summary

- LGADs produced by Teledyne e2v exhibit expected behaviour for IVs and CVs
- Initial implant energy comparisons suggest correlation between implant energy/dose and depletion voltage
- Initial irradiation of diced devices did not affect the high breakdown voltage but as expected, the leakage current did increase overall
- Early gain measurements confirm that our LGADs do indeed have low gain.
- Work on the timing setup has started, and we hope generate plots with a picosecond scale very soon!





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Thank you for listening

Any questions?

